



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Docket No.: INF-138
Serial No.: 10/781,920 Art Unit: 1756
Filed: February 20, 2004 Examiner: TBD
For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

Certificate of Mailing via First Class Mail (37 C.F.R. § 1.8(a))

Date of Deposit: August 13, 2004

I hereby certify that the below listed correspondence is being deposited with the United States Postal Service on the date indicated above as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450.

Certificate of Mailing via First Class Mail (1 page)
Information Disclosure Statement (1 page)
IDS Combined Form PTO/SB/08a and 08b (1 page) citing (5) references
Copies of (4) cited references
Transmittal of Certified Copy of Priority Document (1 page)
Certified Copy of DE 103 07 523.2
Return Postcard

Respectfully submitted,

Natalie Swider

Natalie Swider
Legal Assistant

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
Tel: 972-732-1001
Fax: 972-732-9218



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Attorney Docket: INF-138
Filed: February 20, 2004 Examiner: TBD
Serial No.: 10/781,920 Art Unit: 1756
For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

Mail Stop: Amendment
Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants wish to bring to the attention of the Patent and Trademark Office the information noted on the enclosed combined form PTO/SB/08a & 08b that may be considered material to the examination of the above-identified application.

No fee is due at this time, as this Information Disclosure Statement is being filed pursuant to 37 C.F.R. § 1.97(b)(3), before the mailing of a first Office action on the merits.

Respectfully submitted,

Ira S. Matsil
Attorney for Applicants
Reg. No. 35,272

August 13, 2004

Date

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
(972) 732-1001 (phone)
(972) 732-9218 (fax)



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Wunnicke, et al. Docket No.: INF-138
Serial No.: 10/781,920 Art Unit: 1756
Filed: February 20, 2004 Examiner: TBD
For: Method for Fabricating a Resist Mask for Patterning Semiconductor Substrates

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Transmittal of Certified Copy of Priority Document

Dear Sir:

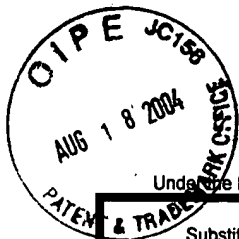
Attached please find a certified copy of the foreign application from which priority is claimed for this case:

Country: Germany
Application Number: 103 07 523.2
Filing Date: February 21, 2003

Respectfully submitted,

Ira S. Matsil
Reg. No. 35,272
Attorney for Applicants

Slater & Matsil, L.L.P.
17950 Preston Rd., Suite 1000
Dallas, TX 75252
Tel: 972-732-1001
Fax: 972-732-9218



Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it displays a valid OMB control number.

PTO/SB/08a (08-03)
Approved for use through 07/31/2006. OMB 0651-0031
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet

1

of

1

Complete if Known

Application Number	10/781,920
Filing Date	2/20/2004
First Named Inventor	Wunnicke, et al.
Art Unit	1756
Examiner Name	TBD
Attorney Docket Number	INF-138

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
	1	US-4,914,006	04-03-1990	Kato, et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ - Number ⁴ - Kind Code ⁵ (if known)				
	2	WO 02/067304 A1	08-29-2002	Hyon, Man-Sok		

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	3	TANAKA, T., et al., "Mechanism of Resist Pattern Collapse during Development Process," Jpn. J. Appl. Phys. Vol. 32, Part I, No. 12B, December 1993, pp. 6059-6064.	
	4	CAO, H.B., et al., "Comparison of Resist Collapse Properties for Deep Ultraviolet and 193 nm Resist Platforms," J. Vac. Sci. Technol. B, Vol. 18, No. 6, Nov/Dec 2000, pp. 3303-3307.	
	5	DÖRFLER, H.-D., "Grenzflächen und Kolloidchemie," VCH, 1994, ISBN 3-527-29072-9, pp. 225-229	

Examiner Signature	Date Considered
-----------------------	--------------------

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹Applicant's unique citation designation number (optional). ²See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.